

**RECEIVED** M-11628 US  
**CENTRAL FAX CENTER**  
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**CLAIM AMENDMENTS**

The following is a complete listing of the pending claims:

1. (Previously presented) A method of making a first-surface optical disk, comprising:
  - providing a father stamper, wherein the father stamper comprises spiral protrusions on a first portion of a first surface and bumps on a second portion of the first surface, the spiral protrusions and bumps corresponding to original laser cuts;
  - coating the first surface of the father stamper with nickel;
  - separating the nickel from the first surface to produce a second stamper having groove recesses and pits on a first surface, wherein the groove recesses are mirror images of the spiral protrusions and the pits are mirror images of the bumps;
  - covering the first surface of the second stamper with a plastic material;
  - separating the plastic material from the second stamper, wherein the plastic material has lands corresponding to the groove recesses of the second stamper and bumps corresponding to the pits;
  - depositing a phase-change material directly over the lands and bumps, wherein the phase-change material is in a first state upon deposition and in a second state after being written to, and wherein the change from the first state to the second state changes the optical phase of the phase-change material in the positive direction, the lands forming a writeable area of the first-surface disk and the bumps forming a read-only area of the first-surface disk ; and
  - depositing a dielectric layer over the phase-change material to form the first-surface optical disk, the dielectric layer being deposited to have a thickness that enhances an optical phase difference between the first and second states of the phase-change material, the first-surface optical disk consisting of no further layers.

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2. (Original) The method of claim 1, wherein the covering comprises injecting the plastic material using an injection molding process.
3. (Original) The method of claim 1, wherein the phase-change material is an SbInSn alloy.
4. (Original) The method of claim 1, wherein the providing comprises: providing a glass master disk with a first and a second principle surface; depositing a photoresist layer on the first principle surface of the disk; removing selected portions of the photoresist layer; depositing nickel over the photoresist layer; and separating the nickel from the photoresist layer to form the father stamper.
5. (Original) The method of claim 4, wherein the removing is by laser ablation.
6. (Original) The method of claim 4, wherein the removing comprises: exposing the selected portions of the photoresist layer; and etching the selected portions.
7. (Original) The method of claim 6, wherein the exposing is performed with a laser and results in the original laser cuts in the photoresist layer.
8. (Original) The method of claim 1, wherein data is written to the lands from exposure by a light source.
9. (Original) The method of claim 4, further comprising rotating the glass master disk and exposing the selected portions with a laser prior to the etching.
10. (Original) The method of claim 4, wherein the deposited photoresist layer is between approximately 20 nm and 120 nm.

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11. (Original) The method of claim 4, wherein the deposited photoresist layer is between approximately 80 and 90 nm.
12. (Cancelled)
13. (currently amended) The method of claim 1-42, wherein the dielectric layer comprises silicon oxynitride.
14. (cancelled)
15. (Original) The method of claim 1, wherein the second stamper is a mother stamper.
16. (Original) The method of claim 1, wherein the father stamper is a first generation stamper, and the second stamper is an even-numbered generation stamper.
17. (Original) The method of claim 1, wherein the second stamper has features that are opposite in polarity to features of the father stamper.
18. (Original) The method of claim 1, wherein the plastic material is a polycarbonate material.
- Claims 19 – 31 (Cancelled)